



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

: Confirmation No. 6344

Yoshio YANASE et al.

: Docket No. 2001-0615A

Serial No. 09/856,982

: Group Art Unit 2877

Filed May 30, 2001

: Examiner Sang H. Nguyen

METHOD FOR INSPECTING
SEMICONDUCTOR WAFER SURFACE

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2877

AMENDMENT AFTER FINAL REJECTION

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Response to the Office Action mailed June 3, 2003, please amend the above-identified application as follows: